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Shinohara et al.

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(54) **FLOW RATE CONTROLLER**

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(73) Assignee: **Fujikin Incorporated**, Osaka (JP)

(**) Term: **14 Years**

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(30) **Foreign Application Priority Data**

Sep. 25, 2007 (JP) 2007-25785

(51) **LOC (9) Cl.** **23-01**
(52) **U.S. Cl.** **D23/245**
(58) **Field of Classification Search** D23/233–237, D23/244–249; 138/45; 62/117, 511, 528; 251/129.04, 129.05; 73/197, 198, 201
See application file for complete search history.

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(57) **CLAIM**

The ornamental design for a flow rate controller, as shown and described.

DESCRIPTION

FIG. **1** is a bottom plan view of the flow rate controller of the present invention.

FIG. **2** is a front elevational view of the flow rate controller of the present invention.

FIG. **3** is a left side elevational view of the flow rate controller of the present invention.

FIG. **4** is a perspective view of the flow rate controller of the present invention when a connector is repositioned.

FIG. **5** is a perspective view of the of the flow rate controller of the present invention.

FIG. **6** is a rear elevational view of the flow rate controller of the present invention.

FIG. **7** is a right side elevational view of the flow rate controller of the present invention; and,

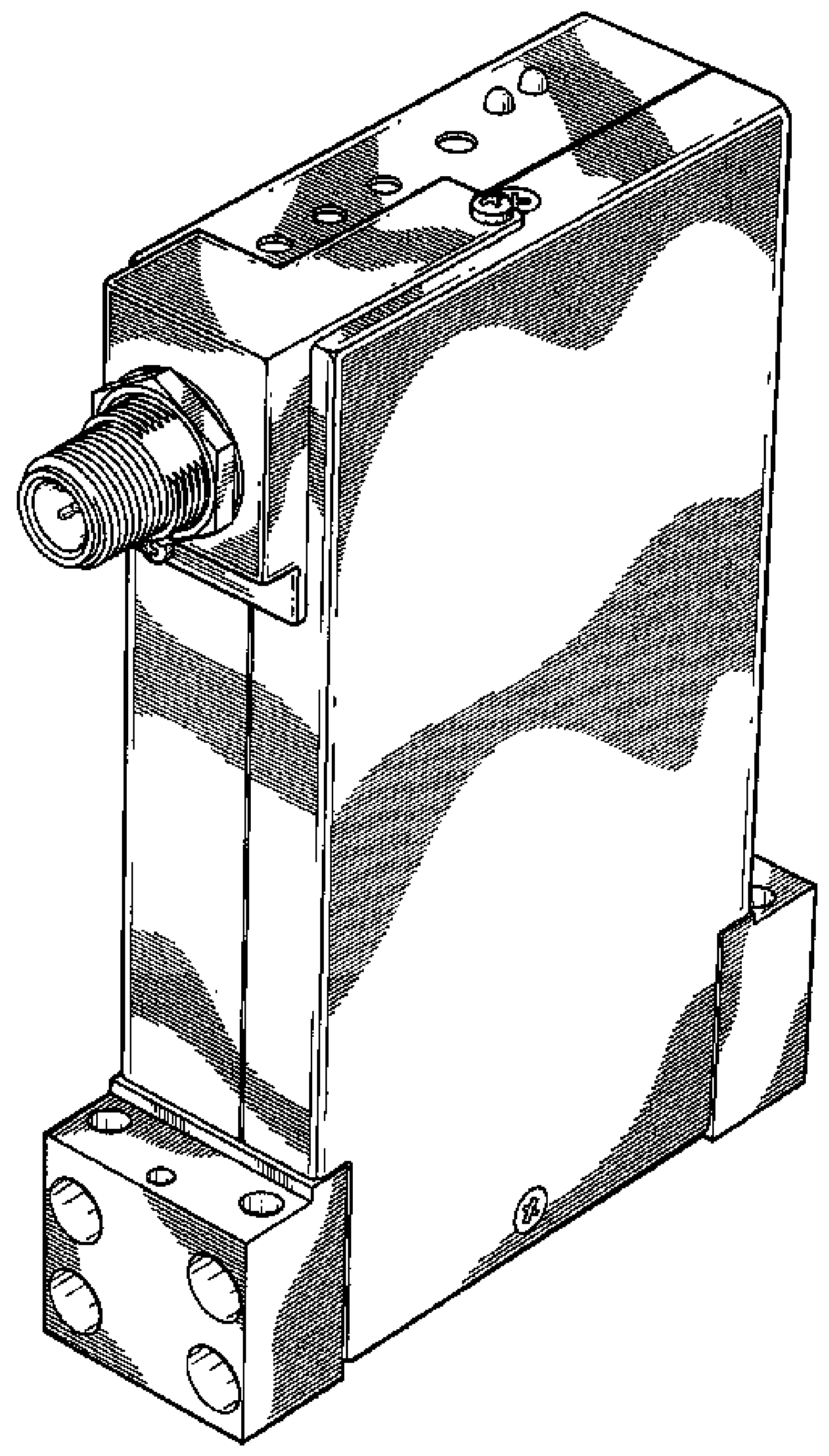
FIG. **8** is a top plan view of the flow rate controller of the present invention.

Any indicia shown in broken lines in the drawings form no part of the design to be patented.

The present article relates to a design of a flow rate controller, which controls fluid including process gas used for fluid supply lines at semiconductor manufacturing facilities, chemical plants, nuclear power plants, petroleum refinery plants and the like.

A flow rate controller is easily connected to a cable by changing the position and direction of the connector even when it is found difficult to connect a cable to a connector because of the relative position of other devices to the controller.

1 Claim, 8 Drawing Sheets



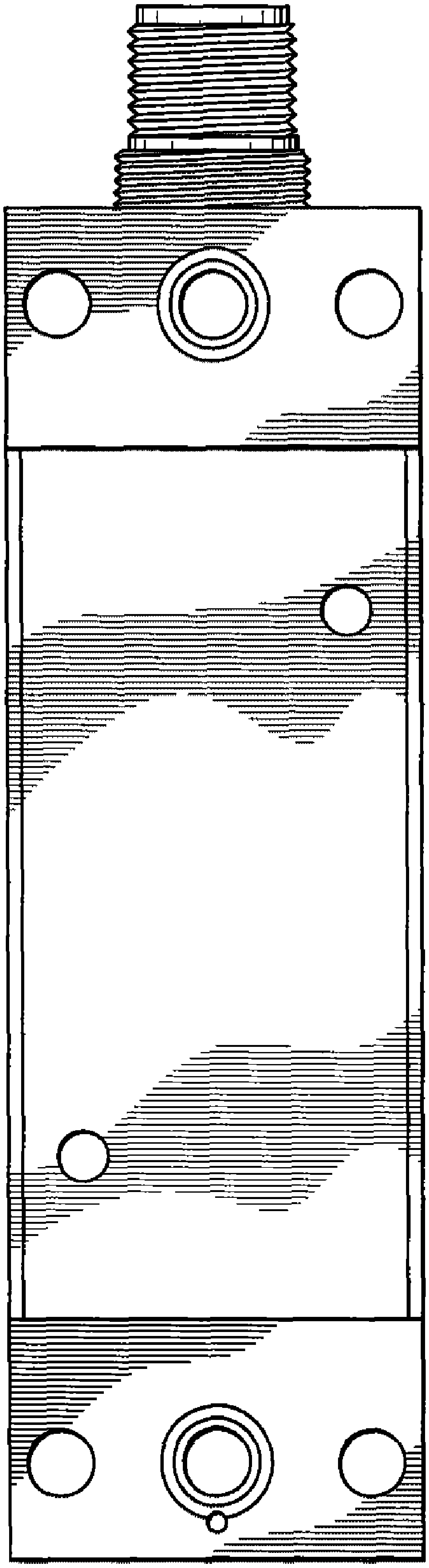


FIG. 1

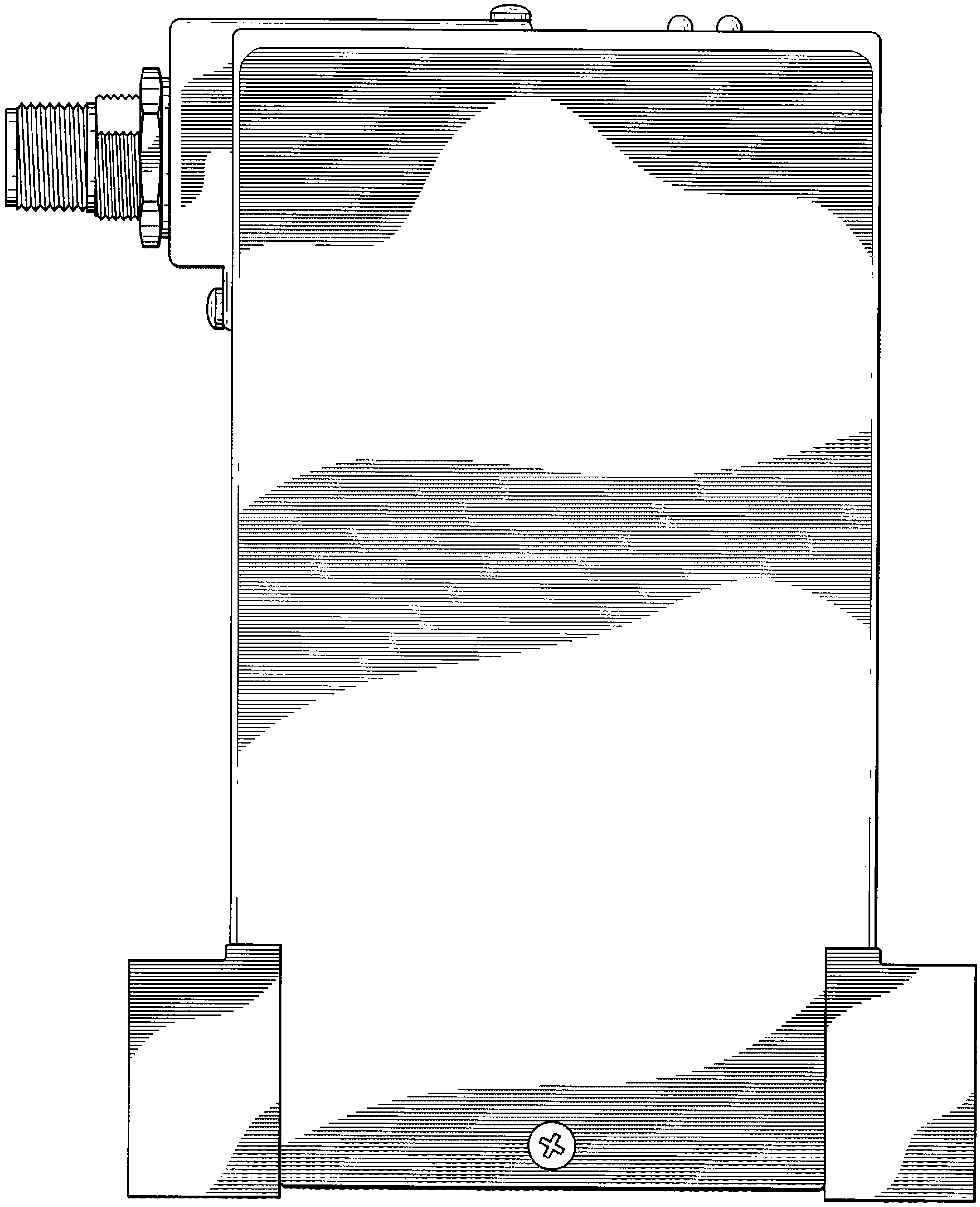


FIG. 2

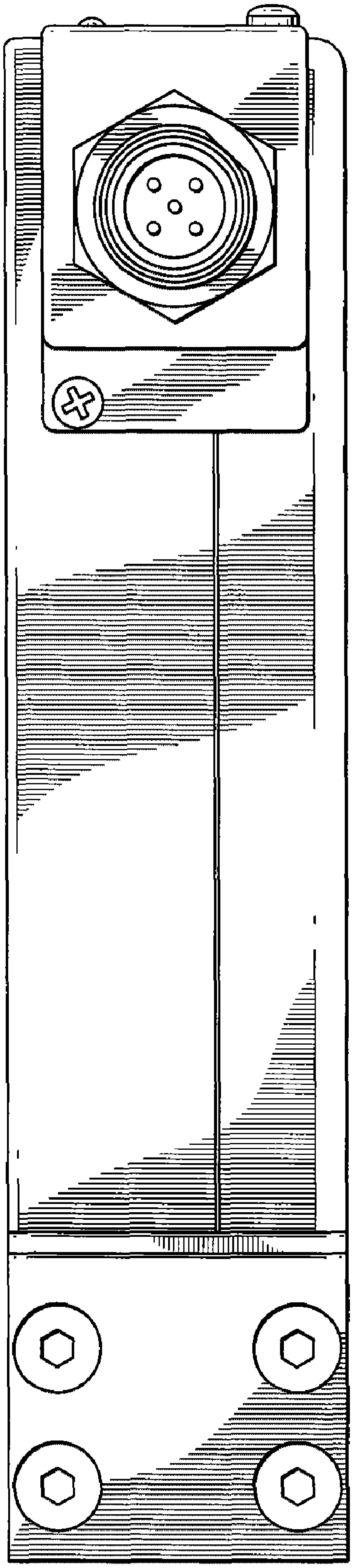


FIG. 3

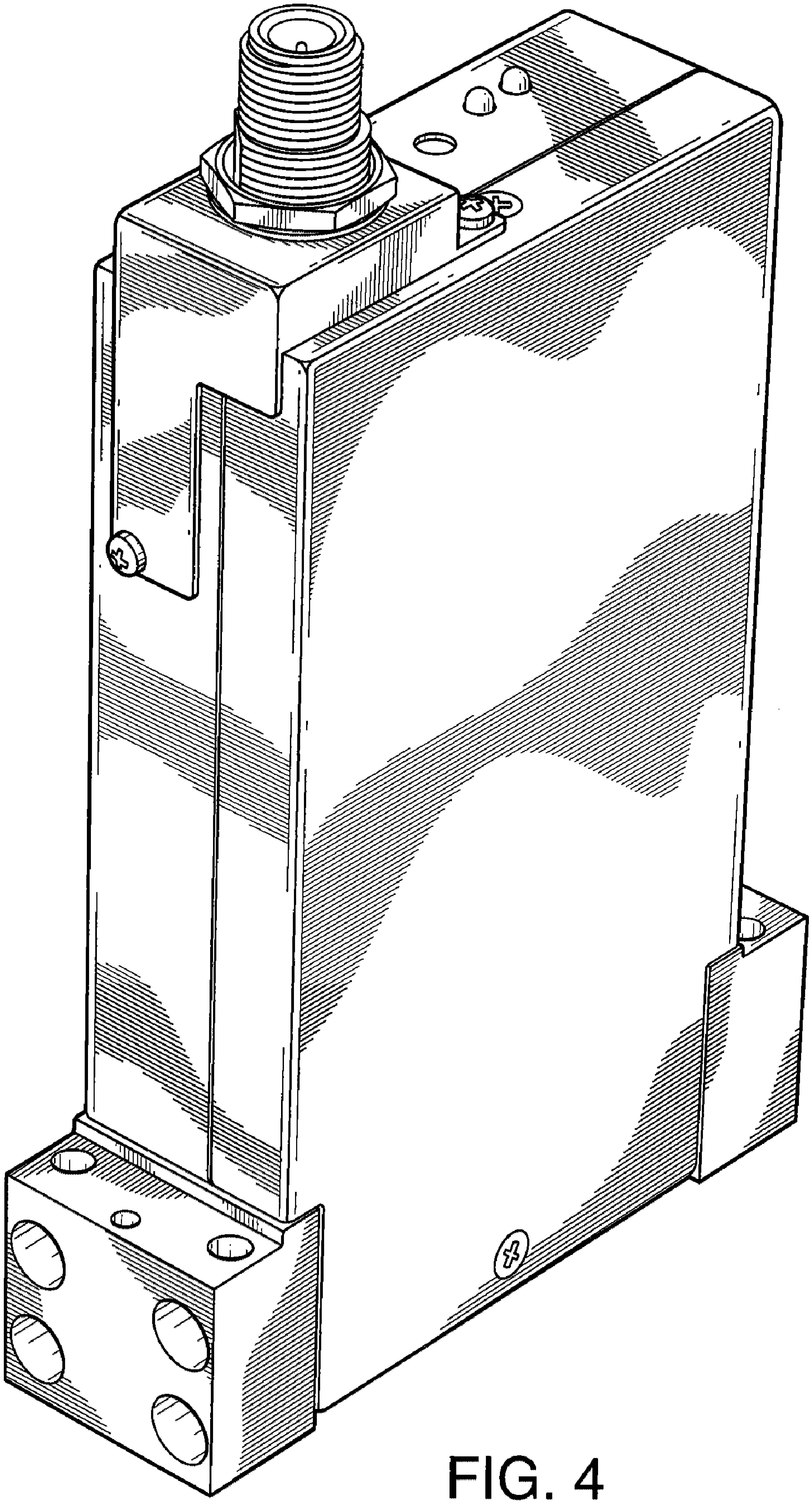


FIG. 4

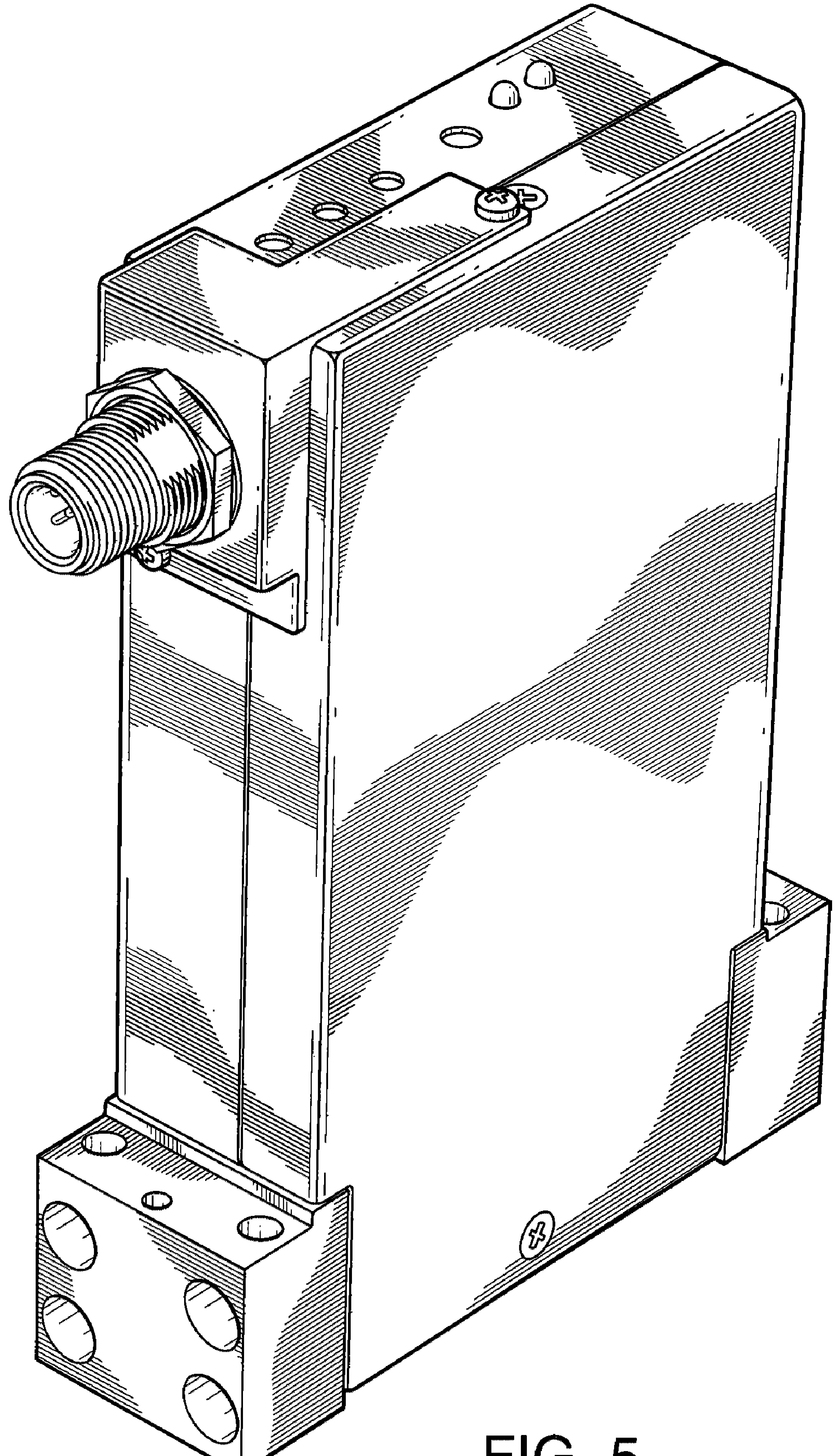


FIG. 5

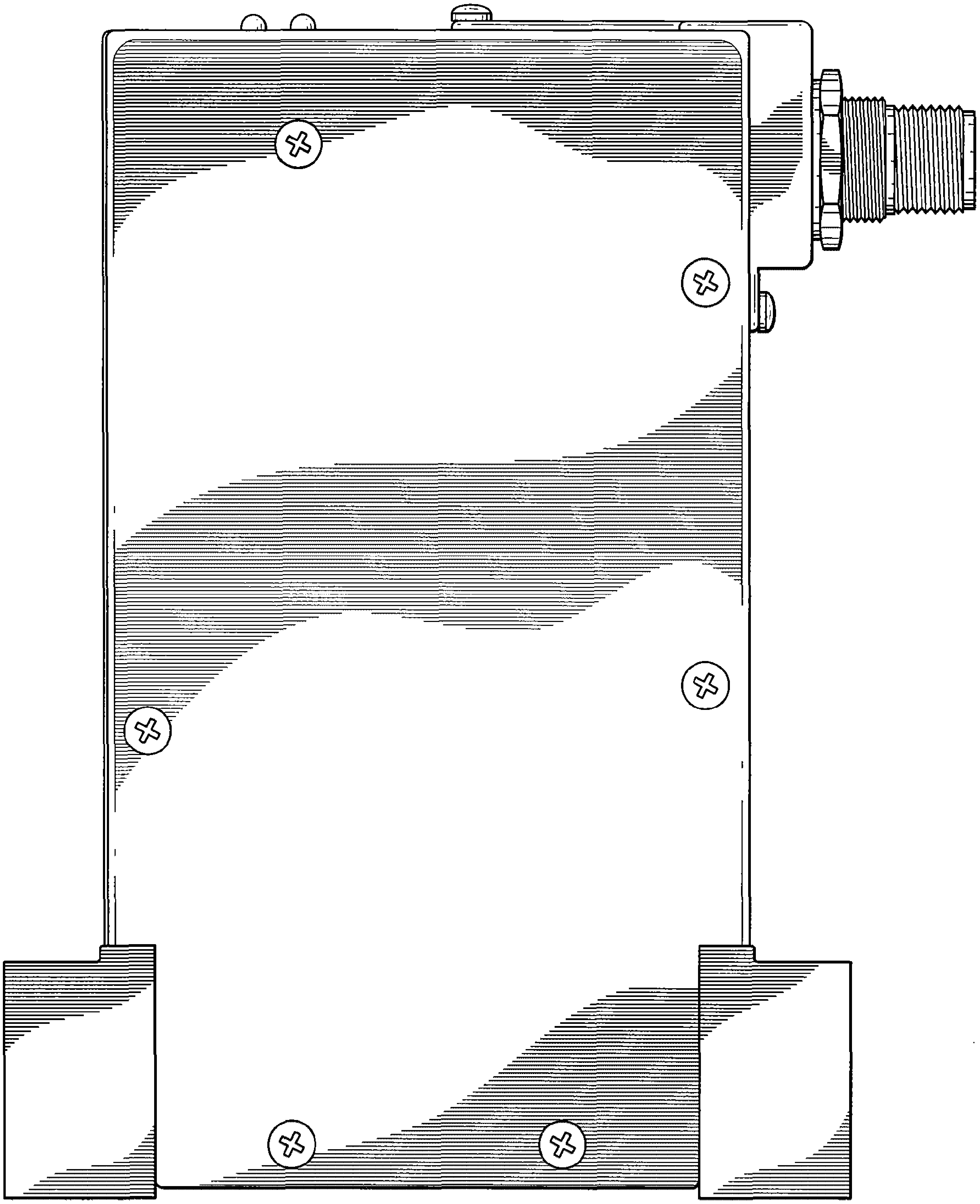


FIG. 6

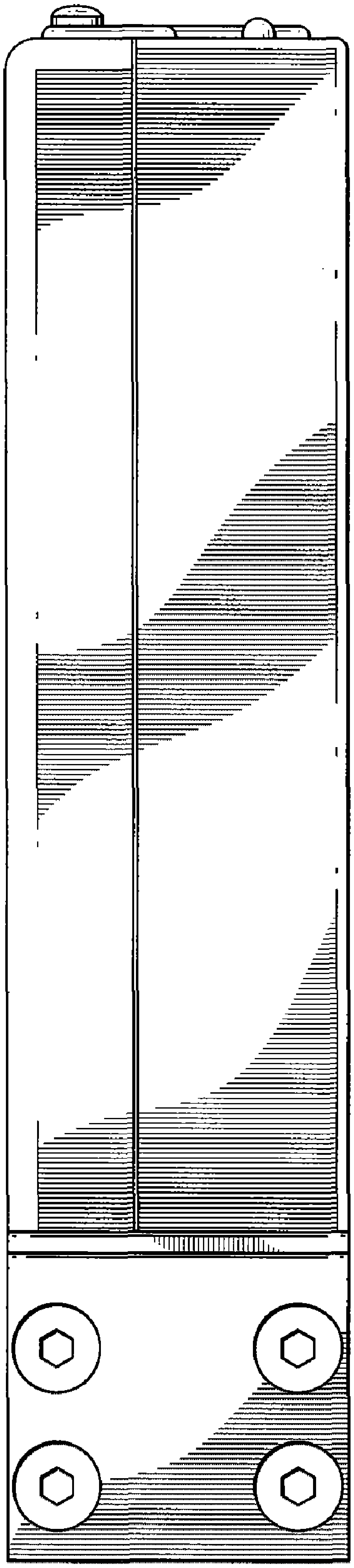


FIG. 7

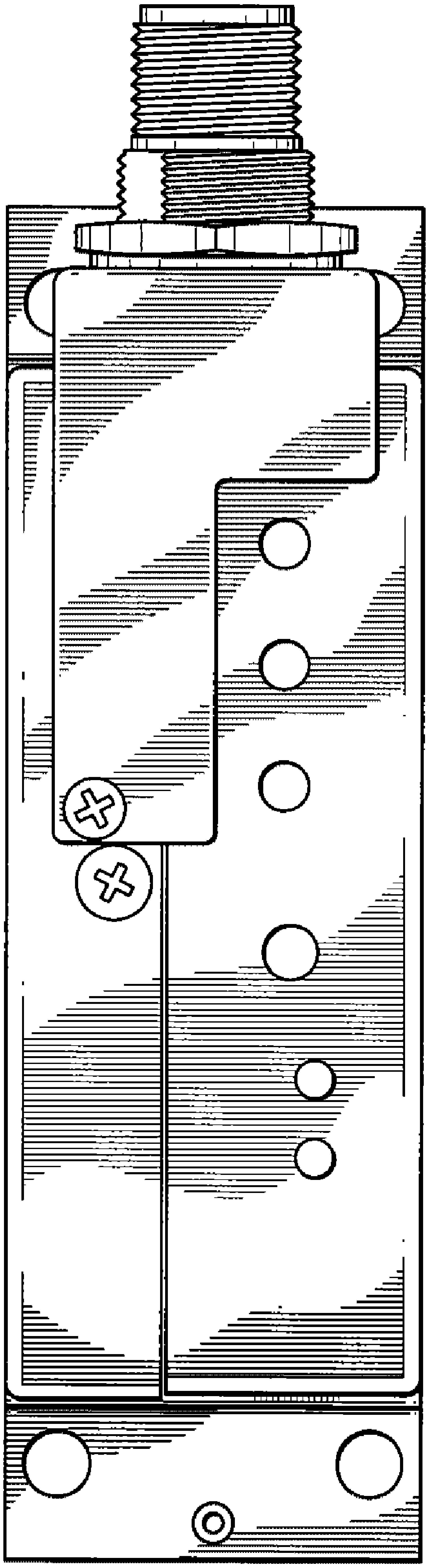


FIG. 8